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## BIB DATA SHEET

CONFIRMATION NO. 7946

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/543,166	07/22/2005	257	2891	ISH-0234		
<b>RULE</b>						
<b>APPLICANTS</b> Hideki Yamanaka, Fukushima, JAPAN; Kiyoshi Demizu, Tokyo, JAPAN; Tadahiro Ohmi, Miyagi, JAPAN; Akinobu Teramoto, Miyagi, JAPAN; Shigetoshi Sugawa, Miyagi, JAPAN;						
<b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP04/00869 01/29/2004						
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2003-030642 02/07/2003						
<b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b>						
Foreign Priority claimed	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No	<input type="checkbox"/> Met after Allowance	<b>STATE OR COUNTRY</b>	<b>SHEETS DRAWINGS</b>	<b>TOTAL CLAIMS</b>	<b>INDEPENDENT CLAIMS</b>
35 USC 119(a-d) conditions met	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No	<input type="checkbox"/> Met after Allowance	JAPAN	9	9	2
Verified and Acknowledged	/DOUGLAS M MENZ/ Examiner's Signature					
<b>ADDRESS</b> RADER FISHMAN & GRAUER PLLC LION BUILDING 1233 20TH STREET N.W., SUITE 501 WASHINGTON, DC 20036 UNITED STATES						
<b>TITLE</b> Silicon semiconductor substrate and its manufacturing method						
<b>FILING FEE RECEIVED</b> 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees		
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